

# **“The 37<sup>th</sup> European Mask and Lithography Conference”**

**EMLC 2022**

**will take place**

**Monday, June 20<sup>th</sup> – Wednesday, June 22<sup>nd</sup>, 2022**

**at the**

**KU in Leuven, Belgium**



**Jubilee Hall for Exhibition & Posters**



**Conference Room**

# **EMLC 2022 – Already Confirmed Presentations:**

## **Tutorial**



**Peter De Bisschop**  
**IMEC**



**Rogier Verberk**  
**TNO**



**Takeo Watanabe**  
**University of Hyogo**

## **Keynote**



**Luc Van den Hove**  
**IMEC**



**Frank E. Abboud**  
**INTEL**



**Jos Benschop**  
**ASML**

## **Invited**



**Lena Bachar**  
**Carl Zeiss SMS**



**Ingo Bork**  
**Siemens EDA**



**Jo Finders**  
**ASML**



**Dirk Hellweg**  
**Carl Zeiss SMT**



**Vicky Philippsen**  
**IMEC**



**Heike Riel**  
**IBM Research**



**Thomas Schmidt**  
**AMTC**



**Frank Sundermann**  
**ST Microelectronics**



**Anna Tchikoulaeva**  
**Lasertec**



**Raluca Tiron**  
**CEA LETI**



**Taguhi Yeghoyan**  
**YOLE**

to be defined

**Best Paper of  
BACUS 2021**

to be defined

**Best Paper of  
PMJ 2022**

# Tuesday, June 21<sup>st</sup>, 2022

## Conference Dinner at the Faculty Club



**Thursday, June 23<sup>rd</sup>, after EMLC 2022: Visit at**



**Organized by Kurt Ronse**

**Director Advanced Litho Program at imec**

**and**

**Uwe Behringer**

**UBC Microelectronics, EMLC2022 Conference Chair**

**ABSTRACT DUE DAY: April 15<sup>th</sup>, 2022**

**[www.emlc-conference.com](http://www.emlc-conference.com)**